

VERSION WITH MARKINGS TO SHOW CHANGES MADE**In the Claims:**

Cancel claims 1, 4, 10, 13 and 20 without prejudice or disclaimer.

2. (Amended) The magnetic medium according to claim [1] 21, further comprising:
- an underlayer between the sealing layer and the magnetic layer; and
- a protective overcoat on the magnetic layer,
- wherein the substrate comprises [a glass or glass-ceramic material comprising] about 0.5 to about 32 wt.% lithium oxide (Li_2O).
3. (Amended) The magnetic recording medium according to claim [1] 21, wherein the surface of the sealing layer is oxidized.
5. (Amended) The magnetic recording medium according to claim [1] 21, further comprising an adhesion enhancement layer between the substrate and the sealing layer.
8. (Amended) The magnetic recording medium according to claim [1] 21, wherein the NiNb sealing layer further comprises about 0.1 wt.% to about 5 wt.% of a material selected from the group consisting of boron, tungsten, tantalum, zirconium and phosphorus.

9. (Amended) The magnetic recording medium to claim [1] 21, further comprising a chromium-vanadium underlayer on the sealing layer, wherein the magnetic layer comprises an alloy of Co, Cr, Pt and Ta.

11. (Amended) The method according to claim [10] 22, further comprising:
sputter depositing an underlayer on the sealing layer prior to said sputter depositing the magnetic layer; and
sputter depositing a protective overcoat on the magnetic layer,
wherein the substrate comprises [a glass or glass-ceramic material comprising] about 0.5 to about 32 wt.% lithium oxide (Li_2O).

12. (Amended) The method according to claim [10] 22, further comprising oxidizing the surface of the sealing layer.

14. (Amended) The method according to claim [10] 22, further comprising sputter depositing an adhesion enhancement layer on the substrate prior to said sputter depositing the sealing layer.

16. (Amended) The method according to claim [10] 22, wherein the thickness of the sealing layer is about 100Å to about 1,000Å.

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17. (Amended) The method according to claim [10] 22, wherein the amorphous NiNb sealing layer further comprises about 0.1 wt.% to about 5 wt.% of a material selected from the group consisting of boron, tungsten, tantalum, zirconium and phosphorus

18. (Amended) The method according to claim [10] 22, comprising sputter depositing the sealing layer using a target comprising at least 12 wt.% Nb.

19. (Amended) The method according to claim [10] 22, wherein the magnetic layer comprises an alloy of Co, Cr, Pt and Ta.

21. (Amended) A longitudinal or perpendicular magnetic recording medium comprising, in this order:

a glass or glass-ceramic substrate comprising Li;

a sealing layer comprising substantially amorphous NiNb directly deposited on the glass or glass-ceramic substrate; and

a magnetic layer,

wherein the sealing layer has a thickness of about 450Å or less and substantially prevents migration of Li from the substrate to the magnetic layer of the magnetic recording medium.

22. (Amended) A method of manufacturing a longitudinal or perpendicular magnetic recording medium, the method comprising:

sputter depositing a sealing layer comprising substantially amorphous NiNb directly on a glass or glass-ceramic substrate comprising Li; and

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sputter depositing a magnetic layer on the sealing layer;

wherein the sealing layer has a thickness of about 450Å or less and substantially prevents migration of Li from the substrate to the magnetic layer of the magnetic recording medium.

23. (Amended) A longitudinal or perpendicular magnetic recording medium comprising, in this order:

a glass or glass-ceramic substrate comprising Li;

a sealing means having a thickness of about 450Å or less for substantially preventing migration of Li from the substrate to a magnetic layer of the magnetic recording medium; and

[a] the magnetic layer.

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